Speeding Up EUV and X-ray Detection for a "Brighter" Future

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Abstract. X-ray imaging and spectroscopy continues to yield innumerable contributions in material science, geological science, and beyond. Looking towards the future – high energy sources (ex. Synchrotrons, XFELS, etc) possess a higher time resolution. These advances are paving the way for the development of new experimental methodologies and opening the door for the acquisition of large amounts of data. Concurrent with the development of these new high energy sources is the need for advances in X-ray camera technologies that can facilitate the high-throughput generation of data and be incorporated in complex experimental geometries. Importantly, it is critical these camera technologies do not compromise on sensitivity and accuracy of detection while exploiting the higher frame rates of these next generation sources to benefit time-consuming applications (e.x. tomography).

We present several detection solutions for the new high energy sources of the future that are brighter and faster than previous generations. These detection solutions, based on sCMOS camera technology, include direct detection methods for the EUV-soft X-ray regimes and indirect detection methods extending sensitivity into the hard X-ray energies. Looking towards higher brilliance sources and high-throughput methodologies we highlight full frame acquisition rates an order of magnitude, or more, faster than comparable CCD technology while maintaining a high QE and lower noise floor. Further discussion around these cameras is framed in the context of how they can contribute to current experimental methodologies, quickly generate large amounts of data, and how they can facilitate the continual evolution in X-ray methodologies into the future.



- where the signal is digitized





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Direct Detection

Indirect Detection

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Lens Coupled

- 10.1098/rsta.2018.0235
- 2. https://www.xtal.iqf.csic.es/Cristalografia/parte_13-en.html
- 10.1002/jemt.22978
- 10.1117/1.JMM.23.4.041404
- 10.1016/j.elecom.2023.107627

Optimizing Throughput and Resolution

ariation of scintillator enables higher higher throughput application. Both images recorded with a 40 keV X-ray source. Left image recorded using 20 µm YAG:Ce scintillator. Right image was acquired using a 150 um CsI:TI scintillator with a 0.1 second exposure. Images courtesy of Crytur.

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General description of the zoneplate based EUV microscope at ALS beamline 11.3.2 (left) and an example image recorded through photomask pellicle (right).⁴

EUV sensitivity, small pixel size, fast image readout, and sCMOS readout architecture enable experimental flexibility in imaging speed while maintaining high image quality, high contrast, and high signal to noise.

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